

ION BEAM DEPOSITION SYSTEM (IBD)

STANDARD FEATURES:

- Electro Polished Stainless Steel Chamber (D-Shaped Box)
- 4" Diameter View Port on Front Door w/ Manual Shutter
- Combination of a Veeco Gridded Divergent Beam Ion Source & Ion Tech Power Supply.
- Mass Flow Controller w/ Digital Readout
- Turbo Molecular Vacuum Pumping System w/ Matching Dual Stage Rotary Vane Pump
- Water cooled target stage for one source. Equipped w/ rotatable four target stage (3" standard target size), for selectively sequential deposition of up to four different materials without breaking vacuum.
- Quartz Crystal Thickness Sensor with Deposition Controller
- Full Range Vacuum Gauge w/ Digital Display & Readout
- Easy Target Mounting



OPTIONAL FEATURES:

- Closed Loop Water Chiller
- Quartz Lamp Heater (from 300° C up to 650° C)
- PLC/PC Controlled System
- SQC 310 Film Thickness Monitor & Deposition Controller
- Cryo Pumping System
- Dry Scroll Pump

- Motorized Shutter Assembly
- Additional Spare Flanges for Future Upgrades
- Manifold for Multiple Mass Flow Controllers for Various Process Gases
- Corrosive Resistant Hardware
 - Pumping System
 - All Metal-Sealed Mass Flow Controllers
 - Vacuum Gauge & Fittings



1 Torr = 1 mm Hg

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